

Multiscale post-processing of metal additive manufactured parts by electro-polishing technology

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Our Mission

Develop green advanced manufacturing technologies meeting the demand of the fourth industrial revolution





Our Expertise

Glass Machining



- Lab-on-Chip
- Multilayer chips
- Micro- to Macro-world interfaces

Post-Processing



- Multiscale electro-polishing
- Down to Ra of 50nm
- Broad range of materials including Titanium



- Complex parts
- Wide range of substrate materials
- Tuning surface wettability

Industry 4.0



- Batch Size 1 production
- Internet of Things (IoT)
- Ultra low-cost tooling



Glass Micromachining





Electropolishing





Room Temperature Nanocoating





Internet of Things





Additive Manufacturing

General functional principle of laser-sintering



Typical metals

- Aluminium alloys
- Cobalt Chrome alloys
- Maraging Steel
- Nickel alloys
- Nickel Chromium alloy
- Stainless steel
- Titanium alloys

Applications

- Aerospace
- Medical
- Automotive
- Lifestyle
- Tooling
- Rapid Prototyping



Additive Manufacturing: Limitations

Staircase effect & semi-melted beads

- Surface quality (1 100 µm R_a)
- Geometrical accuracy
- Surface defects decrease performance





Solutions to overcome limitations:

- Process control (e.g. re-melting, finer powder)
- Post-processing:
 - Electropolishing
 - Mechanical polishing
 - Abrasive flow polishing

- Selective surface smoothing
- control of micro- and nano-roughness



Electropolishing Principle

- Workpiece immersed in electrolyte (e.g. sulphuric acid)
- Anodic dissolution of workpiece

 $M(s) \leftrightarrow M^{+n} + ne^{-1}$

Mass transport mechanism:

- Peaks diffuse at higher rates than recesses
 → anodic leveling
- Random removal of atoms from surface
 - → surface brightening





Surface profile before electropolishing



Surface profile after electropolishing



Electropolishing Limitations

- Acts only on microprofiles (=> requires low initial surface roughness)
- Aqueous acidic solution limits removal of metal species
 → forming TiO₂ layer → stopping removal process
- Acidic electrolytes are very hazardous

Method to overcome limitations

- Pulse Technology → control Nernst diffusion layer
- Water-free electrolytes



Nernst Diffusion Layer Evolution



Nernst diffusion layer control by pulsed current

Short pulses → reducing large asperities (> 100 µm)

Pulse Technology Effect of Pulse Width





Pulse Width [µs]

13

Pulse Technology Effect of Duty Cycle variation





Duty Cycle [%]

Pulse Technology Effect of Polishing Time







Polishing time [min]

Post-process Metal AM Parts

Before EP

After EP





Roughness Profile SLM part Ti-alloy 80.0 Ra 20.5 µm Ra 2.0 µm 60.0 Rz 72.6 µm Rz 7.2 µm 40.0 20.0 [m 0.0 1A -20.0 -40.0 -60.0 -80.0 0.5 1.0 0.0 1.5 2.0 2.5 3.0 3.5 4.0 [mm]

Ra | Rz before + after EP for various alloys





Case Study Roughness Control

- 1. Titanium rod
- 2. 'Spider-web' SLM fabricated Ti-6AI-4V parts





Goal: 1. reduce semi-melted beads (50 μm - 100 μm)
2. understand global reduction in strut thickness
3. optimize parameters for control of roughness and process time



Ti-Spider Web Effect of EP on Bead Removal

Unpolished







Polished (35 min)









Polishing of Inner Surfaces

Unpolished



















Conclusions

- Pulse technology is an effective tool to eliminate surface asperities on AM parts
- Surface roughness is reduced typically by a factor 10-20
- Possible to tune the final roughness
- Possible to polish complex shapes
- Possible to polish inner surfaces



Current industrial partners



What we offer



THANK YOU





Electrochemical Green Engineering Group http://ege.encs.concordia.ca

